High field breakdown characteristics of carbon nanotube thin film transistors

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Abstract

The high field properties of carbon nanotube (CNT) network thin film transistors (CN-TFTs) are important for their practical operation, and for understanding their reliability. Using a combination of experimental and computational techniques we show how the channel geometry (length $L_C$ and width $W_C$) and network morphology (average CNT length $L_t$ and alignment angle distribution $\theta$) affect heat dissipation and high field breakdown in such devices. The results suggest that when $W_C \geq L_t$, the breakdown voltage remains independent of $W_C$ but varies linearly with $L_C$. The breakdown power varies almost linearly with both $W_C$ and $L_C$ when $W_C \gg L_t$. We also find that the breakdown power is more susceptible to the variability in the network morphology compared to the breakdown voltage. The analysis offers new insight into the tunable heat dissipation and thermal reliability of CN-TFTs, which can be significantly improved through optimization of the network morphology and device geometry.

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1. Introduction

Carbon nanotubes (CNTs) are promising and useful materials for many applications due to their good thermal, electrical, optical and mechanical properties [1, 2]. Several studies have been performed in the past decade to explore and develop devices which could leverage the excellent properties of individual CNTs and their two- and three-dimensional (2D and 3D) networks [2–8]. In particular, CNT network thin film transistors (CN-TFTs) have been explored for a wide range of applications such as flexible displays, sensors, antennas, etc [2, 4, 7–13]. Significant efforts have been made in recent years aimed at overcoming fabrication challenges to improve the performance of these devices [3, 14–18, 11]. However, fewer studies have been focused on the heat dissipation in these devices, which is an important aspect of CN-TFT operation [19, 20]. CNT networks are typically supported on thermally insulating substrates such as glass or plastic, which have very low thermal conductivity and where the excessive self-heating in CN-TFTs under high field operation can lead to the breakdown of these devices [19, 20].

CN-TFTs with large aspect ratios ((channel length $L_C$/channel width $W_C$) $\gg$ 1) have been investigated previously to achieve higher ON/OFF current ratios. Narrow $W_C$ and large $L_C$ in CN-TFTs (figure 1) help in reducing the number of metallic percolating paths in unsorted CNT networks which typically have a 1:2 metallic (M) to semiconducting (S) ratio [3, 21]. However, such high aspect ratios can also lead to substantial variability and non-uniformity in the ON current [22]. In addition, a CNT network is comprised of individual single-walled CNTs of
uniformity in CN-TFT performance characteristics. Device parameters in order to engineer thermal reliability and presented here provides new insight into optimization of the CNT length and alignment distribution. The analysis reliability of CN-TFTs can be improved by optimizing with both $W$ and $L$ distributions of we consider a general case employing different log-normal network alignment on the breakdown behavior. Subsequently, we develop the breakdown characteristics and their standard deviations for smaller and larger $W_C$ at various $L_C$ for random networks with constant CNT length, $L_t$. Next, we systematically vary the alignment of CNTs in the network for a given $L_C$, $W_C$ and $L_t$ to study the effect of network alignment on the breakdown behavior. Subsequently, we consider a general case employing different log-normal distributions of $L_t$ in conjunction with several alignment distributions for a given $L_C$ and $W_C$. The results suggest that when $W_C$ is greater than the average $L_t$, $P_{BD}$ remains independent of $W_C$ and varies linearly with $L_C$. The variation in the distribution of alignment and $L_t$ does not significantly affect $V_{BD}$. However, we find that $P_{BD}$ increases with both $L_C$ and $W_C$. In particular, for large $W_C$, $P_{BD}$ varies linearly with both $W_C$ and $L_C$. Our results suggest that the thermal reliability of CN-TFTs can be improved by optimizing the CNT length and alignment distribution. The analysis presented here provides new insight into optimization of the device parameters in order to engineer thermal reliability and uniformity in CN-TFT performance characteristics.

2. Methodology

CNTs synthesized by the arc discharge method are used as starting materials for all the samples. The diluted solution containing single-walled CNTs and surfactant is vacuum filtered through a mixed cellulose ester membrane to form a CNT network. After the filtration through the membrane, the film is washed with a copious amount of water to remove residual surfactants. The network is then transferred to a supporting substrate of $\text{SiO}_2$ ($t_{\text{ox}} = 300 \text{ nm}$) on highly n-doped $\text{Si}$ ($t_{\text{Si}} = 500 \mu \text{m}$) with predefined electrical contacts and then the filter is dissolved [25]. After the film transfer to the substrate, it is soaked in acetone overnight to remove residual cellulose and is further cleaned by annealing at 230$^\circ$C for 1 h in ambient. The device channels are patterned by photolithography and/or electron-beam lithography (for submicron width dimensions). The Si substrate acts as a back-gate, and unless otherwise noted we set the gate-to-source voltage ($V_{\text{GS}} = -40 \text{ V}$) such that both $\text{M}$ and $\text{S}$ type CNTs are in the ‘ON’ state ($V_{\text{GS}}$ is significantly below the threshold voltage) while the source-to-drain voltage ($V_{\text{SD}}$) is increased until network breakdown. Device characterization and breakdown are conducted in air at room temperature ($T_0 = 25^\circ\text{C}$).

For computational analysis, we employ a coupled electro-thermal model to analyze the current, power, and temperature distribution in the device [20, 21, 26, 27]. A brief description of the governing equations is provided below.

2.1. Thermal transport

The thermal transport in the device consisting of CNT network, oxide layer and Si substrate is simulated using the diffusive energy transport equations, which can be written in the following non-dimensional form [27]:

$$\frac{d^2\tilde{\xi}_j}{ds^2} + \tilde{G}_S(\tilde{\xi}_O - \tilde{\xi}_i) + \sum_{i \in \text{intersecting tubes } j} \tilde{G}_C(\tilde{\xi}_j - \tilde{\xi}_i) + \frac{d}{L_s} \frac{\tilde{q}_i}{Q} = 0 \quad (1)$$

$$\nabla^2 \tilde{\xi}_O + \sum_{i=1}^{N_{\text{tube}}} \tilde{G}_S \gamma(\tilde{\xi}_i - \tilde{\xi}_O) = 0 \quad (2)$$

$$\nabla^2 \tilde{\xi}_{\text{Si}} = 0. \quad (3)$$
Here, \( \xi = (T - T_{\infty})/(Q^* \, d_k/k_i) \) is the non-dimensional form of the temperature \( T \), where \( T_{\infty} \) denotes the ambient temperature, \( Q^* \) is a reference power per unit volume, \( d \) is the diameter of the CNT, and \( k_i \) is the axial thermal conductivity of the CNT. \( \xi \), \( \xi_{\text{OX}} \) and \( \xi_{\text{Si}} \) are the non-dimensionalized temperatures of a section of the 4th CNT, oxide, and Si, respectively. An asterisk symbol is used to refer to length variables which are non-dimensionalized by \( d \). Equation (1) governs the temperature of a CNT along its axial direction (length variable \( s \)); the second and third terms in this equation represent thermal interactions at the CNT–oxide interface and at CNT–CNT junctions, respectively. \( \eta_i \) is the volumetric Joule heating term within the CNT which is obtained from the solution of electrical transport equations (discussed below). \( \tilde{G}_C \) and \( \tilde{G}_S \) represent the non-dimensional thermal contact conductance at CNT–CNT junctions and the CNT–oxide interface respectively. Their values (\( \tilde{G}_C = 10^{-7} \) and \( \tilde{G}_S = 2 \times 10^{-4} \)) are obtained by comparing the power–voltage curves obtained from the experiments against the simulations [20]. Equation (2) describes the temperature in the oxide layer and the second term in this equation represents the CNT–oxide thermal interaction, which is summed over all the CNTs. The parameter \( \gamma \) in this term characterizes the contact geometry. Equation (3) describes the temperature of the Si layer.

We use a constant temperature boundary condition \( T = 298 \, \text{K} \) at the bottom surface of the Si substrate, while a convective boundary condition [20, 27] is imposed at the top surface of the oxide layer. The lateral boundaries have been assumed to be thermally insulated. The boundary conditions have been selected to simulate the experimental conditions.

### 2.2. Electrical transport

The electrical transport in the carbon nanotubes has been described by Poisson and current continuity equations as follows [13, 21, 27]:

\[
\frac{d^2 \psi_i}{ds^2} + \frac{\rho_i}{\varepsilon} = \frac{(\psi_i - V_G)}{\lambda^2} + \sum_{j \neq i} \frac{(\psi_j - \psi_i)}{\lambda_{ij}^2} = 0, \quad (4)
\]

\[
\nabla \cdot J_{pi} + \sum_{j \neq i} C_{ij}^p (p_j - p_i) = 0, \quad (5)
\]

\[
\nabla \cdot J_{ni} + \sum_{j \neq i} C_{ij}^n (n_j - n_i) = 0, \quad (6)
\]

Here, \( \psi \) is the electrostatic potential, \( V_G \) is the gate voltage, \( \rho \) is the net charge density, \( \varepsilon \) is the permittivity of the CNT. The third term in Poisson’s equation represents the gating effect [27] with screening length \( \lambda = (\varepsilon_{\text{CNT} \, \varepsilon_{\text{OX}} d}/\varepsilon_{\text{OX}})^{0.5} \). Here, \( \varepsilon_{\text{CNT}} \) and \( \varepsilon_{\text{OX}} \) are the dielectric constants for the CNT and gate oxide respectively and \( \varepsilon_{\text{OX}} \) is the oxide thickness. The fourth term in equation (4) describes the inter-tube electrostatic interaction at CNT–CNT junctions with screening length \( \lambda \sim d \). Equations (5) and (6) are current continuity equations for holes and electrons respectively, where \( J \) is the current density given by drift–diffusion equations. The hole and electron charge densities are represented by \( p \) and \( n \), respectively. The second term, \( C_{ij}^p (n_j - n_i) \) or \( C_{ij}^n (p_j - p_i) \), in the continuity equations represents charge (electrons or holes) transfer across the CNT–CNT junctions. The charge transfer coefficient \( (3) \) is considered to be zero for M–S junctions to account for their low contact conductance compared to the M–M and S–S junctions [28]. These assumptions have been adopted in a previous study, where the model has successfully explained the experimental observations [5, 20, 22]. Experimental studies have also shown that the electrical resistance at heterogeneous junctions (M–S) is two orders of magnitude larger than at homogeneous junctions (M–M or S–S) [28]. The electrical conductivity of M-CNTs is considered to be five times higher than that of S-CNTs according to experimental measurements [25].

The numerical values of the major parameters in equations (1)–(6) are provided in a separate table in the supplementary document (available at stacks.iop.org/Nano/24/405204/Mmedia). These electro-thermal equations are solved self-consistently to obtain the current, potential and temperature distribution in the CN-TFTs. Heterogeneous networks of M and S type CNTs (1:2 ratio) are considered in all simulations unless specified otherwise.

The model provides comprehensive details of the temperature and power distribution within the CNT network and thermal transport across the substrate (Si) and insulator (SiO\(_2\)). Since these details are very difficult to obtain directly from experiments, the model serves as an essential tool in analyzing the high field transport and breakdown of CN-TFTs. The numerical model is validated by comparing the simulation results with experimental data (see section 3.1). Under high field conditions, Joule heating can lead to oxidation of the CNTs in air if the temperature exceeds the breakdown temperature \( T_{BD} \approx 600 \, ^\circ\text{C} \), resulting in breakdown of the devices [19, 20, 27]. Thus, during this electrical breakdown process, the power dissipation in the device reaches a maximum value near \( T_{BD} \), and then drops quickly to zero as the current paths within the network reform and oxidize, reaching catastrophic device failure. A back-gated device configuration has been selected for the experiments as it facilitates experimental measurements [19, 25]. All simulation results presented in this work are averaged over a large number of devices (\( n \approx 100 \)) unless specified otherwise. Both the mean and the standard deviation of the breakdown characteristics are presented to understand the variability in the breakdown behavior for different device geometry and network morphology parameters.

### 3. Results and discussion

#### 3.1. Channel geometry

We first analyze the effect of \( L_C \) and \( W_C \) on the breakdown characteristics. From the perspective of the device breakdown, the two important metrics are \( P_{BD} \) and \( V_{BD} \). Figure 2(a) shows the power dissipation in the device as a function of \( V_{SD} \) for three different cases of \( L_C \), where \( n = 15 \) CNTs \( \mu \text{m}^{-2} \), \( W_C = 100 \, \mu\text{m} \), and \( L_4 = 2 \, \mu\text{m} \). We see a very close agreement of the
Figure 2. (a) Measured and simulated power dissipation in a CNT network versus source-to-drain voltage ($V_{SD}$) for three different channel lengths ($L_C = 5, 10, 15 \mu m$). Simulation results are presented for individual devices here. For a given $L_C$, the power reaches a peak value and then drops quickly to zero as the CNT network breaks down due to the excessive Joule heating and CNT oxidation in air. The value of $V_{SD}$ corresponding to the peak power ($P_{BD}$) is referred to as the breakdown voltage, $V_{BD}$. (b) $V_{BD}$ versus $L_C$, and (c) $P_{BD}$ versus $L_C$. The error bar represents a 95% confidence interval. The device is in the ON state at gate voltage $V_{GS} = -40$ V. Device width $W_C = 100 \mu m$; CNT length $L_t = 2 \mu m$; network density $\rho = 15$ CNTs $\mu m^{-2}$. Parts (b) and (c) contain simulation results which are averaged over 100 devices.

Figure 3. Numerical results for (a) power versus $V_{SD}$ (the arrow indicates increasing channel width) and (b) power per unit width versus $V_{SD}$ for several channel widths ($W_C = 4, 10, 20, 30, 40 \mu m$), channel length $L_C = 10 \mu m$, and network density $\rho = 30$ CNTs $\mu m^{-2}$. Note that the power per unit width becomes invariant with respect to $W_C$ for sufficiently high $W_C$. (c) The $\sigma_{norm}$ of breakdown voltage ($V_{BD}$) versus $L_C$ and (d) the $\sigma_{norm}$ of peak power ($P_{BD}$) versus $L_C$. Here $\sigma_{norm}$ = standard deviation/mean.

Simulation results with the experiments. It should be noted here that the simulation curves shown in figure 2(a) have been specifically selected out of 100 sample simulations. CN-TFTs with smaller $L_C$ show less electrical resistance which in turn leads to higher current (i.e., higher power dissipation) at a given $V_{SD}$ [5, 22]. This causes a device with smaller $L_C$ to break earlier (i.e., at a lower $V_{SD}$). We find that both $V_{BD}$ and $P_{BD}$ scale linearly with $L_C$ (figures 2(b) and (c)). The error bars in these figures indicate the variation in breakdown characteristics of the random networks. The size of the error bar represents a 95% confidence interval for $V_{BD}$ (or $P_{BD}$). The experimental values for both $V_{BD}$ and $P_{BD}$ fall well within the range of error bars estimated from the simulations. For a given network density, the number of percolating pathways decreases as $L_C$ increases. As previously reported [22], the ON current shows greater variation when the network density is decreased. Lowering the density is equivalent to reducing the number of percolating pathways, which also occurs when $L_C$ is increased, and therefore the error bars increase as $L_C$ increases. These results suggest that the variability in the breakdown for a given device geometry and network density can be substantial and require due consideration when predicting the device reliability [25].

Figure 3(a) shows the breakdown behavior of CN-TFTs for $W_C = 4, 10, 20, 30, 40 \mu m$ at $L_C = 10 \mu m$, $L_t = 2 \mu m$, and $\rho = 15$ CNTs $\mu m^{-2}$. The curves in figure 3(a) resemble a ‘bell’ shape due to the statistical averaging. It can be observed that the $V_{BD}$ does not change with $W_C$. Further, we find $P_{BD}$ to be directly proportional to the width when $W_C/L_t > 2$ (figure 3(b)). We also note that the normalized standard deviations ($\sigma_{norm}$) of $V_{BD}$ (figure 3(c)) and $P_{BD}$ (figure 3(d)) increase when $L_C$ is increased or $W_C$ is decreased. For $W_C/L_t \leq 2$, we observe relatively large $\sigma_{norm}$ due to significant incremental change in the number of percolating pathways [30]. We find that for $\rho = 15$ CNTs $\mu m^{-2}$, $L_C = 10 \mu m$, and $W_C/L_t = 2$, less than 30% of the random networks out of 100 samples have a percolating path between source and drain. The probability of forming a percolating path further decreases as we increase $L_C$ for $W_C/L_t \leq 2$. Therefore, we employ a denser network to study the breakdown behavior for $W_C/L_t \leq 2$.

Figure 4 shows the dependence of the breakdown behavior on $L_C$ for narrow width devices ($W_C/L_t = 0.75, 1, 1.5, 2$) at $\rho = 30$ CNTs $\mu m^{-2}$. We find that $V_{BD}$ is nearly invariant of the $W_C$ for $W_C/L_t \geq 1$ (figure 4(a)). $P_{BD}$ follows width-dependent scaling with $L_C$ such that higher width leads to greater change in $P_{BD}$ per unit change in $L_C$ (figure 4(b)).
Figure 4. Numerical results for (a) breakdown voltage ($V_{BD}$) and (b) normalized peak power (with respect to $W_C$) in the CNT network versus channel length ($L_C$) for smaller channel widths ($W_C$). (c) The $\sigma_{\text{norm}}$ of $V_{BD}$. (d) Peak power (PP) versus $L_C$. Here, network density $\rho = 30 \text{ CNTs} \text{ \(\mu\)m}^{-2}$.

Figure 5. Scanning electron microscopy (SEM) images of CN-TFTs after complete breakdown for different channel lengths ($L_C = 6.5$, $16.5$, $21.8 \mu$m) and widths ($W_C = 1.3$, $2.4$, $4.7 \mu$m). The breakdown gap length ($L_{BD}$) in the CN-TFT increases as $L_C$ is increased; however, $L_{BD}$ does not show much variation when the width is changed.

A similar trend is observed in the experiments, as shown in the supplementary information (section S1 available at stacks.iop.org/Nano/24/405204/mmedia). We note that the $\sigma_{\text{norm}}$ of $V_{BD}$ (figure 4(c)) and $P_{BD}$ (figure 4(d)) remain nearly invariant of $L_C$ for $W_C/L_t \geq 1$ and $\sigma_{\text{norm}}$ decreases as $W_C$ increases at a given $L_C$. Overall, we note that larger values of $L_C$ and $W_C$ correspond to better device reliability as they lead to larger $V_{BD}$, greater $P_{BD}$, and better uniformity in device characteristics.

Previous studies [19, 20, 25, 31] on CN-TFT breakdown show that the network breaks in a zigzag pattern across the channel when $W_C$ is much greater than $L_t$. In the current study, we examine this breakdown pattern in CN-TFTs when $W_C$ is comparable to $L_t$. Scanning electron microscopy (SEM) images from the experiments show that the breakdown pattern remains zigzag when $L_C$ is small (a few microns) for different values of $W_C$, as shown in figures 5(a), (d) and (g). Also, the length ($L_{BD}$) of the breakdown gap region (shown in figure 5(g)) is observed to be less than the average $L_t$, which indicates a highly localized burning of CNTs. Further, $L_{BD}$ increases as $L_C$ is increased for a given $W_C$ but does not change much with respect to $W_C$ for a given $L_C$ (figure 5). This trend underlines the role of the temperature profile before the breakdown and the electrostatic effects of the broken CNTs during the breakdown process. For devices with larger $L_C$, the temperature profile is more flat away from the contacts, which leads to larger $L_{BD}$. In addition, a higher electrostatic effect from the broken tubes amounts to a greater induced electric field in the unbroken neighboring CNTs. This electrostatic effect is proportional to the applied voltage between the source and the drain at the breakdown (i.e., $V_{BD}$) [31]. As $V_{BD}$ increases linearly with $L_C$, the breakdown gap also follows nearly the same trend.
Figure 6. (a) The schematic illustrates the alignment of a CNT. The average alignment ($\theta_{avg}$) of the CNT network is defined such that for a specific value of $\theta_{avg}$, a CNT in the network is allowed to make any angle between $-2\theta_{avg}$ and $2\theta_{avg}$ with equal probability. Hence, by this definition, $\theta_{avg} = 45^\circ$ corresponds to a random network, and $\theta_{avg} = 0^\circ$ means perfectly aligned CNTs. Examples of heterogeneous CNT networks with $\theta_{avg} = 13^\circ$ and $\theta_{avg} = 36^\circ$ are given in (b) and (c) respectively. Metallic (M) CNTs are shown in brown, semiconducting (S) CNTs in blue; the M:S network density ratio is 1:2.

Figure 7. (a) Power dissipation versus source-to-drain voltage ($V_{SD}$) for different alignments ($\theta_{avg}$) of the CNTs in the network. (b), (c) $V_{BD}$ and $P_{BD}$ versus $\theta_{avg}$ respectively. Here, $L_s = 2 \mu m$, $L_C = 10 \mu m$, $W_C = 10 \mu m$, $\rho = 15$ CNTs $\mu m^{-2}$. The metallic to semiconducting CNT ratio in the network is 1:2 and the electrical conductivity ratio is 5:1. It should be noted that very few (<10%) devices have connected pathways at very low angle ($\theta_{avg} < 10^\circ$). However, this number improves (e.g. >70%) for $\theta_{avg} = 13^\circ$ significantly for higher $\theta_{avg}$.

3.2. Network morphology

3.2.1. Variable alignment angle with constant CNT length.

In order to investigate the effect of CNT alignment on TFT breakdown behavior, we consider several alignment distributions of the CNTs in the network. We define the average alignment ($\theta_{avg}$) such that for a specific value of $\theta_{avg}$, a CNT in the network is allowed to make any angle between $-2\theta_{avg}$ and $2\theta_{avg}$ with equal probability, as shown in figure 6.

Figure 7(a) shows a plot of power dissipation versus $V_{SD}$ for different network alignments (from $\theta_{avg} = 9^\circ$ to $45^\circ$). It is observed that for a highly aligned network ($\theta_{avg} < 10^\circ$), the devices show negligible current due to the reduced number of percolating pathways bridging the source and drain contacts. However, as we increase $\theta_{avg}$, the current increases due to the increasing number of percolating pathways. Previous studies [21] have also suggested that the ON current depends on the alignment and reaches a maximum at $\theta_{avg} \sim 30^\circ$, which is consistent with our results for $V_{SD} < 20$ V, as shown in figure 7(a). For the breakdown behavior analysis, we analyze the $P_{BD}$ and $V_{BD}$ dependence on $\theta_{avg}$. We find that $V_{BD}$ first decreases sharply and then shows a zigzag pattern with increasing $\theta_{avg}$. Two local minima are observed at $\theta_{avg} = 22^\circ$ and $36^\circ$ (figure 7(b)). $V_{BD}$ lies in the small range of 26–29 V for $\theta_{avg} > 10^\circ$, which suggests a weak dependence of $V_{BD}$ on alignment. $P_{BD}$ increases linearly as we increase $\theta_{avg}$ up to $27^\circ$ and two ‘local’ maxima are observed at $\theta_{avg} = 27^\circ$ and $40^\circ$ (figure 7(c)).

In order to explore the nature of this dependence, we examine the breakdown pattern of the CNT networks. It should be noted that we consider the network to be composed of M and S type CNTs in 1:2 ratio. A Schottky barrier has been assumed to be present between metallic and semiconducting CNTs, and M–S junctions are considered to be electrically insulating since M–M or S–S junction conductance can be two orders of magnitude higher than M–S junction conductance [28]. We also showed in our previous work [20] that in general heat transfer across the CNT junctions is negligible in comparison to heat transfer across the CNT–SiO$_2$ interface. Therefore the poor thermal contact conductance between CNTs makes crossed-CNT contacts thermally insulating as well [20]. This implies that the network can be considered to be composed of two independent ‘parallel’ networks of different densities and conductivities. Therefore the breakdown behavior and characteristics discussed are due to the combined breakdown behavior of pure metallic and semiconducting networks. Figure 8(a) shows a plot of power dissipation versus $V_{SD}$ for different $\theta_{avg}$ at $\rho = 15$ CNTs $\mu m^{-2}$ for a homogeneous network (semiconducting CNTs only). We find that $V_{BD}$ and $P_{BD}$ exhibit only one minimum ($\theta_{avg} = 20^\circ$) and maximum ($\theta_{avg} = 36^\circ$) respectively (figures 8(b) and (c)). A similar
Figure 8. (a) Plot of power dissipation in the device versus source-to-drain voltage ($V_{SD}$) for different alignments ($\theta_{avg}$) of CNTs in a purely semiconducting network. (b), (c) Breakdown voltage ($V_{BD}$) and peak power ($P_{BD}$) are plotted versus $\theta_{avg}$. Here $L_t = 2 \, \mu m$, $L_C = 10 \, \mu m$, $W_C = 10 \, \mu m$, and $\rho = 15 \, \text{CNTs} \, \mu m^{-2}$.

Figure 9. A bar plot of (a) breakdown voltage ($V_{BD}$) and (b) peak power dissipation ($P_{BD}$) versus network alignment ($\theta_{avg}$) for metallic ($\rho = 7.5 \, \text{CNTs} \, \mu m^{-2}$) and semiconducting ($\rho = 15 \, \text{CNTs} \, \mu m^{-2}$) networks. The letters ‘m’ and ‘M’ denote the locations of minima and maxima respectively. The metallic to semiconducting CNT density ratio is 1:2 which is same as that in a typical unsorted CNT network.

3.2.2. Variable alignment angle with log-normal distribution of CNT length. We previously discussed the dependence of the breakdown behavior on the alignment of CNTs where $L_t$ was kept constant. In this section, we study the breakdown behavior for a more general case where both CNT length and alignment are varied according to their respective distributions. Figure 10 illustrates the log-normal distribution of $L_t$ in the network. Here, the device size is $L_C \times W_C = 5 \, \mu m \times 5 \, \mu m$, and $\rho = 15 \, \text{CNTs} \, \mu m^{-2}$. All CNTs are considered to be semiconducting to analyze only the effects of length and alignment distributions. We consider three different cases of log-normal length distributions (average $L_t$, $<L_t> = 1, 1.15$ and $1.3 \, \mu m$) and nine cases of alignment distributions (range of $\theta_{avg} = 9^\circ$ (highly aligned network) to $45^\circ$ (random network)). The log-normal distribution is given by the following equation:

\[ f(L_t, \mu, \sigma) = \frac{1}{L_t \sigma \sqrt{2\pi}} \exp\left[-\frac{(\ln L_t - \mu)^2}{2\sigma^2}\right] \]  

where $f$ is the probability distribution function, $L_t$ is the CNT length, $\mu$ is the mean and $\sigma$ is the standard deviation of the CNT length. It should be noted that the log-normal distribution of CNT length has a practical significance as this distribution is typically observed in the experiments [25, 32]. We expect the log-normal distribution to affect the reliability and breakdown characteristics of homogeneous CNT networks, as a previous study [24] reported that the resistivity of heterogeneous networks varies with change in the parameters of the log-normal distribution.
Figure 11. A bar plot of (a) breakdown voltage ($V_{BD}$), (b) normalized standard deviation ($\sigma_{norm}$) of $V_{BD}$, (c) peak power ($P_{BD}$) and (d) normalized standard deviation ($\sigma_{norm}$) of $P_{BD}$ for varied alignment and length distributions of the CNT network. $V_{BD}$ shows little variation as the alignment or length distribution is changed, whereas $P_{BD}$ shows a strong correlation with alignment; this correlation changes significantly as the length distribution is changed.

The results (figure 11) suggest that the effect of the alignment on the breakdown behavior strongly depends on the $L_t$ distribution. We find that an $L_t$ distribution with higher $\langle L_t \rangle$ provides higher $P_{BD}$. Also, the $\theta_{avg}$ corresponding to the maximum $P_{BD}$ decreases when $\langle L_t \rangle$ is increased. In other words, better thermal reliability can be obtained when $\langle L_t \rangle$ is higher and the network is partially aligned. Interestingly, $V_{BD}$ does not show much variation despite the fact that $P_{BD}$ changes significantly. The trend of $P_{BD}$ can be explained on the basis of the trade-off associated with the number of percolating paths and the resistance of these paths. At lower $\theta_{avg}$, the number of percolating paths in the channel will be lower, but the resistance of these pathways will be also low due to the lower number of CNT junctions in these pathways. For higher values of $\theta_{avg}$, the network tends toward a random distribution and the number of connections in the network increases, i.e., the number of effective percolative pathways increases, but the CNT junction density per pathway also increases. Therefore a maximum current (or power) should be achieved for some intermediate $\theta_{avg}$ which offers optimal channel resistance. As mentioned earlier, this optimal value of $\theta_{avg}$ decreases as $\langle L_t \rangle$ increases. We also note that the standard deviations in $V_{BD}$ and $P_{BD}$ show little variation with change in $\langle L_t \rangle$ and $\theta_{avg}$. However, their normalized values ($\sigma_{norm}$) change due to the variation in the mean values of the respective variables. More details about power variation with $V_{SD}$ have been included in the supplementary information (section S3 available at stacks.iop.org/Nano/24/405204/mmedia).

4. Conclusion

In summary, we have studied the effects of channel geometry and network morphology on the high field breakdown of carbon nanotube network thin film transistors (CN-TFTs). We applied both experimental and computational techniques to examine the heat dissipation in the devices and provide an in-depth analysis of two important characteristics ($P_{BD}$ and $V_{BD}$) relevant to the breakdown process in CN-TFTs. We observed that the breakdown characteristics vary significantly with the channel length, but their dependence on the channel width is relatively very small. In a heterogeneous network, the breakdown characteristics and their relation with the network morphology vary with the ratio of metallic and semiconducting CNTs in the network. The analysis of breakdown behavior of CN-TFTs for various log-normal CNT length distributions and several alignment distributions suggests that the heat dissipation and thermal reliability of CN-TFTs can be significantly improved by optimizing the network morphology parameters.

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